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## Rutherford Backscattering and Auger Spectroscopy of Mercuric Iodide Detectors

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#### Abstract

Palladium contacts on mercuric iodide have been studied using Rutherford Backscattering Spectroscopy and Auger Electron Spectroscopy. Results on actual detector contacts show some intermixing of both mercury and iodine with the palladium. To investigate the role of processing variables as a possible cause of this effect we have fabricated "model contacts" at low temperatures (T~100 K) and analyzed *in situ*. The results demonstrated that significant interdiffusion occurs at temperatures as low as 225 K. We conclude that excessive heating during contact deposition could prove to be detrimental to device performance and that the use of cooled substrates during processing should be explored.

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Interest in mercuric iodide as a room temperature x-ray detector has increased rapidly over the last few years. Crystals are now grown larger and with greater purity than ever before. However, to make a detector, or any other electrical device, it is necessary to form high quality electrical contacts to the crystal. At present, the deposition and formation of contacts is both poorly understood and irreproducible among the different laboratories engaged in detector fabrication. For example, EG&G has found gold to be a very poor contact material for HgI2 presumably because of readily formed compounds of gold, mercury and iodine. On the other hand, Tadjine et. al. [1] have formed stable contacts with gold. Similar discrepancies are found for other surface related effects, for example, Nicolau [2] has found HNO3 to be a useful electrochemical etchant prior to contact deposition but that a KI solution worked poorly. Precisely the opposite results were obtained by EG&G which now uses a standard KI chemical etch based process for cutting and polishing prior to evaporation of contacts.

The present work represents the first experimental study using modern surface science techniques to investigate the metal-insulator interface between the contact and the mercuric iodide crystal. Both Rutherford Backscattering Spectroscopy (RBS) and Auger Electron Spectroscopy (AES) have been used in these studies. In all cases reported here, the contact material was palladium, which has generally been the most successful choice. The contacts investigated included ones fabricated at Sandia by the same techniques used to make actual working detectors, as well as ones fabricated in an ultra high vacuum chamber on a HgI2 substrate cooled to low temperature to avoid sublimation. These latter contacts are termed "model contacts" since they were produced in a manner slightly different than for production detectors. The utility of these model contacts is that they can be readily analyzed by Auger electron spectroscopy in situ during fabrication at temperatures where interdiffusional effects and chemical reaction rates between the metal and the HgI2 are minimized. Measurements on actual detector contacts were made with both RBS and AES.

#### Rutherford Backscattering Spectroscopy (RBS)

RBS was performed with 2 MeV <sup>4</sup>He+ particles at a backscattering angle of 150° on specimens which were inserted into the vacuum chamber after Pd contacts were evaporated onto the mercuric iodide crystals in a separate deposition system. For the deposition process, the polished HgI<sub>2</sub> crystals are inserted into a diffusion pumped bell jar where the Pd is deposited by evaporation from a hot tungsten filament. The total time between the insertion into and removal from the deposition chamber was less than 10 min. (the actual evaporation step took place in less than one minute). RBS spectra were obtained for the sample at room temperature, the Pd contact serving as a barrier to sublimation of the underlying HgI<sub>2</sub> crystal during the course of the measurements. The barrier is desirable both from the standpoint of reducing contamination to the vacuum chamber and of losing sample material from the surface region which could lead to stoichiometry changes.

The energy of the backscattered <sup>4</sup>He<sup>+</sup> particles is measured with a silicon surface barrier detector and depends on two things: the mass of the target atom that produces the turn around event and the total path length of the <sup>4</sup>He<sup>+</sup> ion in the solid. Since the particle loses energy due to electronic excitation as it traverses the sample, the particles exhibiting the greatest energy loss represent those that penetrated deepest into the sample. The recoil energy of the backscattered ions depends on the target mass according to simple classical ideas of scattering; thus, the heavier target particles give rise to higher energy backscattered particles [3].

Figure 1 shows the RBS spectrum from an "as received" detector fabricated at room temperature. The leading step in the spectrum, at approximately 1.8 MeV, is due to ions backscattered from mercury atoms at the Pd/HgI<sub>2</sub> interface. Since mercury is the heaviest atom of the target, ions backscattered from it are highest in energy, even though some energy is lost in traversing the evaporated Pd film. The next feature in the spectrum, a step at approximately 1.72 MeV, is due to backscattering from two different regions: iodine at the contact interface and palladium at the free surface. Iodine, being lighter than mercury, produces a lower energy backscattered <sup>4</sup>He+. Palladium, being lighter still, would have its

edge appear at even lower energy except that the incident ions can scatter directly off its surface without traversing the metal film. In the present experiment, these two regions are not resolved. At still lower energy in the spectrum, at 1.68 MeV, a downward going step can be seen. This feature is due to palladium at the contact interface region. No evidence of impurities was found in these measurements, but it should be borne in mind that RBS is not very senstive to the most likely contaminants, carbon and oxygen.

Figure 1 also contains the results of model calculations of RBS using the RUMP code [4]. Two examples are shown differing only in the assumption of the thickness of the Pd contact, 200 and 500 Å. The two simulations nicely bracket the experimental curve. The relative heights of the steps indicate that the stoichiometry is close to that of  $HgI_2$ . The calculation includes broadening based on measurement of the instrument resolution. Some additional broadening is apparent which suggests that the contact may not be perfectly uniform in thickness. Moreover, both steps in the experiment have tails which extend to higher energy than the calculations. This suggests some interdiffusion of the mercuric iodide towards, and possibly onto the Pd surface.

#### Auger Electron Spectroscopy (AES)

We have also studied the Pd/HgI<sub>2</sub> interface using Auger electron spectroscopy [5]. The surface sensitivity of this technique greatly exceeds that of RBS because of the short escape depth of the Auger electrons (< 10Å). Two types of specimens were investigated: those fabricated as described in the RBS section, above (i.e. actual detector contacts), and those on model contacts grown *in situ* in the UHV chamber. For the former, specimens were inserted into the UHV system (base pressure 1 x 10<sup>-10</sup> Torr) through a rapid sample insertion stage onto a liquid nitrogen cooled assembly. Transfer and cool down times were on the order of 10 minutes or less. Once the sample was cooled to T<150 K, the AES spectra were taken using a 3–keV primary electron beam and a double pass CMA spectrometer (PHI model 15-255G).

"Model contacts" were produced in situ by first depositing a thin layer ( $\sim$ 5000 Å) of HgI<sub>2</sub> from a room temperature capsule containing HgI<sub>2</sub> which was inserted into the UHV system to within  $\sim$  1 cm of a cold ( $T\approx$ 100 K) saphire

substrate mounted on a small heater assembly. The saphire had a thin palladium contact which had previously been evaporated onto it in the bell jar. Growth of the HgI<sub>2</sub> film could be monitored by observing the development of interference fringes as the layer thickness increased. After HgI<sub>2</sub> deposition, Pd could be evaporated *in situ* using a small tungsten wire source. A chromel alumel thermocouple was mounted directly onto the sapphire to monitor temperature changes during evaporation and for later annealing treatments. A temperature increase of less than 5 K was typically observed during Pd deposition.

On all detector contacts fabricated using a standard Pd deposition process onto room temperature HgI<sub>2</sub> crystals, significant, in some cases as much as one monolayer, quantities of both mercury and iodine were found on the surface of the palladium contact. Figure 2 shows an example of an Auger spectrum for an "as received" detector contact fabricated at room temperature. The contact covers the entire free surface of the HgI<sub>2</sub> crystal, approximately 1 cm<sup>2</sup>. The electron beam is focussed to approximately 1 mm<sup>2</sup>. In addition to Pd, both Hg and I are seen on the surface of the contact. This suggested to us that interdiffusion of the mercuric iodide and the palladium may have occurred during the deposition at room temperature and that a more detailed examination of the kinetics during interface formation would be very beneficial. To this end we developed techniques described above to deposit both HgI<sub>2</sub> and Pd onto a liquid nitrogen cooled substrate in the UHV system.

For thick layers of mercuric iodide grown at substrate temperatures of less than 150 K, Auger spectroscopy showed that the surface stoichiometry was close to that of HgI<sub>2</sub>. However, warming the sample to 260 K caused significant changes in the surface composition, a decrease in the iodine signal and an increase in the Hg signal were observed in the AES spectra indicating a change in stoichiometry in the direction of mercurous iodide. Any studies of the kinetics associated with the interface between the metallic contact and the mercuric iodide must therefore necessarily be done at temperatures below 260 K.

To examine interdiffusional effects we have constructed layered sandwich structures of Pd/HgI<sub>2</sub>/Pd on top of sapphire, where the mercuric iodide layer was less than  $\sim 1~\mu m$  thick (based on the number of interference fringes

observed during growth). The outermost Pd layer was less than or equal to approximately 500 Å (still transparent but with a slight metallic sheen evident visually). These structures which were initially grown at T~100 K were then isochronally annealed (5 min.) at successively higher temperatures, cooled back to 100 K and examined with AES. After depositing the Pd film, only palladium was visible in the Auger spectra. Figure 3 shows the Auger signal (peak-to-peak height) for iodine and mercury after various annealing treatments. Two types of regions on the sample were examined: regions which had not yet been exposed to the primary AES beam (3 keV), designated "virgin" areas, and those which had seen the electron beam previously, designated "damaged" areas. Measurements of the sample temperature during the AES indicated temperature rises of less than 2 K. The excellent thermal conductivity of the substrate and the thinness of the film insures that the temperature of the sample in the region of the incident electron beam is not appreciably raised.

The top two curves in the figure are for the virgin regions and have been shifted upward to avoid overlap with the bottom two curves. It is clear that the iodine and mercury track one another for both sets of curves. For annealing treatments below 175 K both I and Hg are essentially zero and cannot be distinguished from the noise in the AES spectra. At 200 K, however, the virgin regions exhibit appreciable iodine and mercury signals, with further increases occurring after the 275 K anneal. The final anneal to room temperature was for only 2 minutes, but nevertheless exhibits some further increases. Overall, the behavior shown for the damaged regions is similar except for the fact that the onset for the iodine and mercury signals is shifted to slightly higher temperatures. Thus, the beam damage appears to "fix" the interface somewhat, it delays the interdiffusion to a higher temperature. Note that this is in the opposite direction as would occur, for example, by beam heating effects since for that case the temperature of the sample in the area of the incident electron beam would be higher than the temperature measured by the thermocouple. An alternate explanation is that the primary beam may desorb the I and Hg through electronstimulated desorption.

A second example of sequential heating of a Pd/HgI<sub>2</sub>/Pd sandwich structure is shown in figure 4. In this case, the data were all taken on damaged regions and more annealing cycles were obtained in order to follow the kinetic process in

more detail. The same general trends are observed: a rapid increase in iodine and mercury levels is seen at and above the 225–K annealing temperature. For the data shown in this figure, all of the annealing treatments were for 5 minutes.

#### Summary

It is clear from both the RBS and AES results presented here that palladium contacts on HgI2 cannot be viewed as an undisturbed metallic film resting on top of a perfect mercuric iodide crystal. From these studies we can identify at least two phenomena that may affect the stoichiometry of the contact interface region and which therefore may affect the electrical properties of the contact. The first of these is the preferential loss of iodine from the surface upon vacuum exposure. This implies that during vacuum deposition processes, a thin layer of mercurous iodide may form prior to or during Pd evaporation depending on the temperature of the crystal and the length of time it remains under vacuum prior to evaporation. Secondly, above 200 - 225 K there is significant intermixing of Pd with the substrate crystal. If this interpenetration becomes severe, the metallic nature of the contact will be lost causing failure of the device (we have observed this effect for Cu contacts on HgI2). Both of these effects indicate that one should take care to prevent excessive heating of the sample during contact deposition. We suggest that processing techniques explore the use of cooled substrates during contact deposition. Sputter deposition should also be explored especially since this technique is less likely to raise the temperature of the substrate in a production environment.

The effects presented here could also be important in the degradation of detectors over long periods of time. Certainly, prevention of storage at elevated temperatures should avoid long term degradation and enhance the survivability.

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- [3] see for example: <u>Ion Beam Handbook for Material Analysis</u>, Edited by: J. W. Mayer and E. Rimini, (Academic Press 1977).
- [4] developed by L. Doolittle at Cornell University.
- [5] see for example: <u>Photoelectron and Auger Spectroscopy</u>, T. A. Carlson (Plenum, 1975).

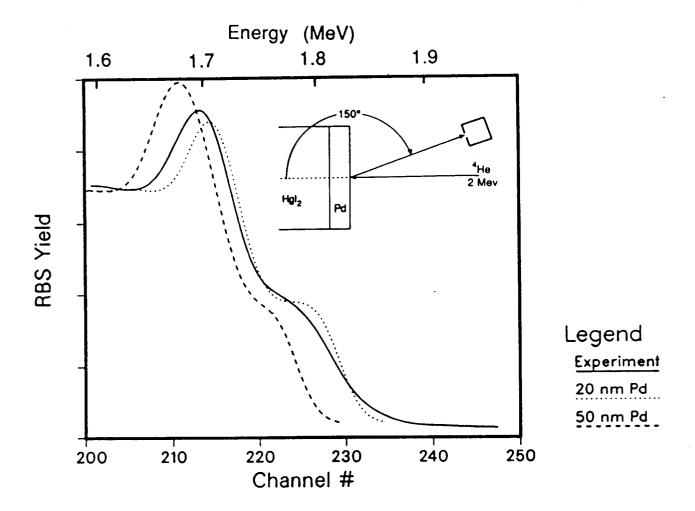


Figure 1. 2 MeV Rutherford Backscattering Spectrum of an "as received" Pd contact on a mercuric iodide detector. Also shown are two computer simulations which bracket the experimental spectrum.

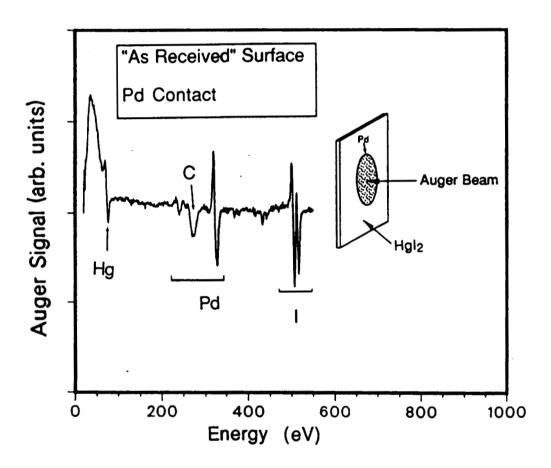


Figure 2. Auger spectrum of an "as received" Pd contact on a mercuric iodide detector showing the existence of mercury and iodine on top of the contact. The contact covers the entire crystal surface (approximately 1 cm<sup>2</sup>) and the Auger beam samples a small portion of it (approximately 1 mm<sup>2</sup>).

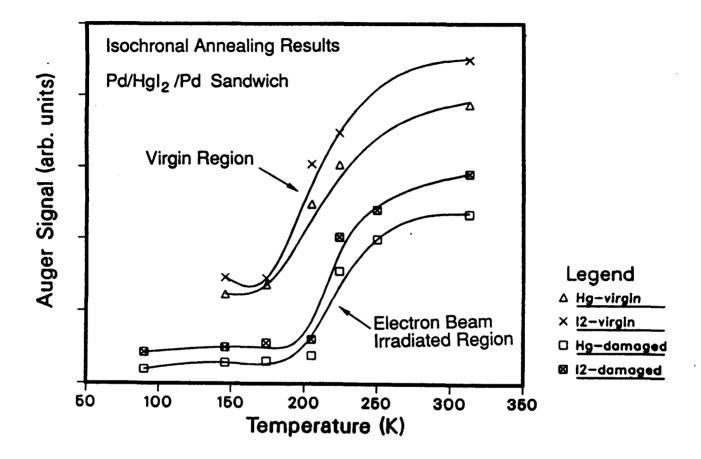


Figure 3. Annealing sequence for a Pd/HgI<sub>2</sub>/Pd sandwich structure. Except for the 2 minute anneal at 300 K, all the anneals were performed for a duration of 5 minutes. Two types of regions were investigated, those which had never previously seen the electron beam (shifted upward in the figure) and those which had previously seen the electron beam.

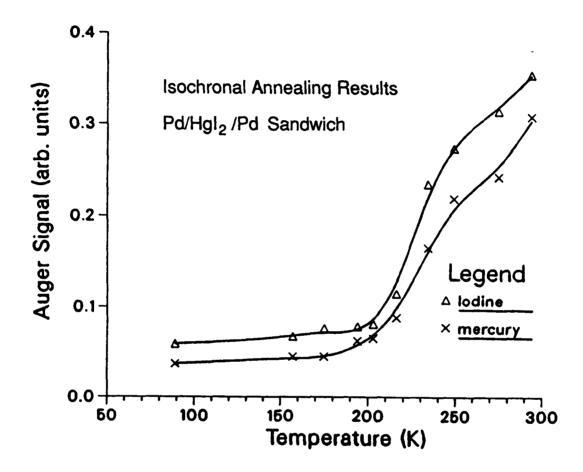


Figure 4. Similar to figure 3 except all anneals performed for 5 minutes and only regions of the sample that had see the electron beam are plotted. The sequence has more annealing cycles so as to display the kinetics more completely.

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